BJ KIM LAB.



Dw- 304

[Micro Components & Systems]

Centre for International Research on MicroNano Mechatronics

http://www.kimlab.iis.u-tokyo.ac.jp/

NEMS, Bio-MEMS/Bio-Sensor

Department of Precision Engineering

Advanced NEMS

and nanowire fabrication

Micromachined tools for investigation of nanoworld

Our research goals are to build nanosystems and fabricate nanoscale devices, in particular for bio-sensing in singular level, through both bottom-up and top-down approaches. Key technologies concentrate on high-resolution surface patterning with simple, low-cost techniques such as micro-contact printing (μ CP), probe lithography, flexible polymer based soft lithography, and micro even nano shadow-masks patterning.

Based on these studies on nano/micro components systems for the fabrication of novel nano devices, we investigate to develop various micro sensors for biological applications, such as i) MEMS device for electrical/physical characterization of single cell, ii) single cell electroporation microchip for gene transfection, and iii) temperature measurement on resistively heated nanowires for the study on single molecules, etc.



Fabrication of various nano channels with micro chambers for single DNA detection